

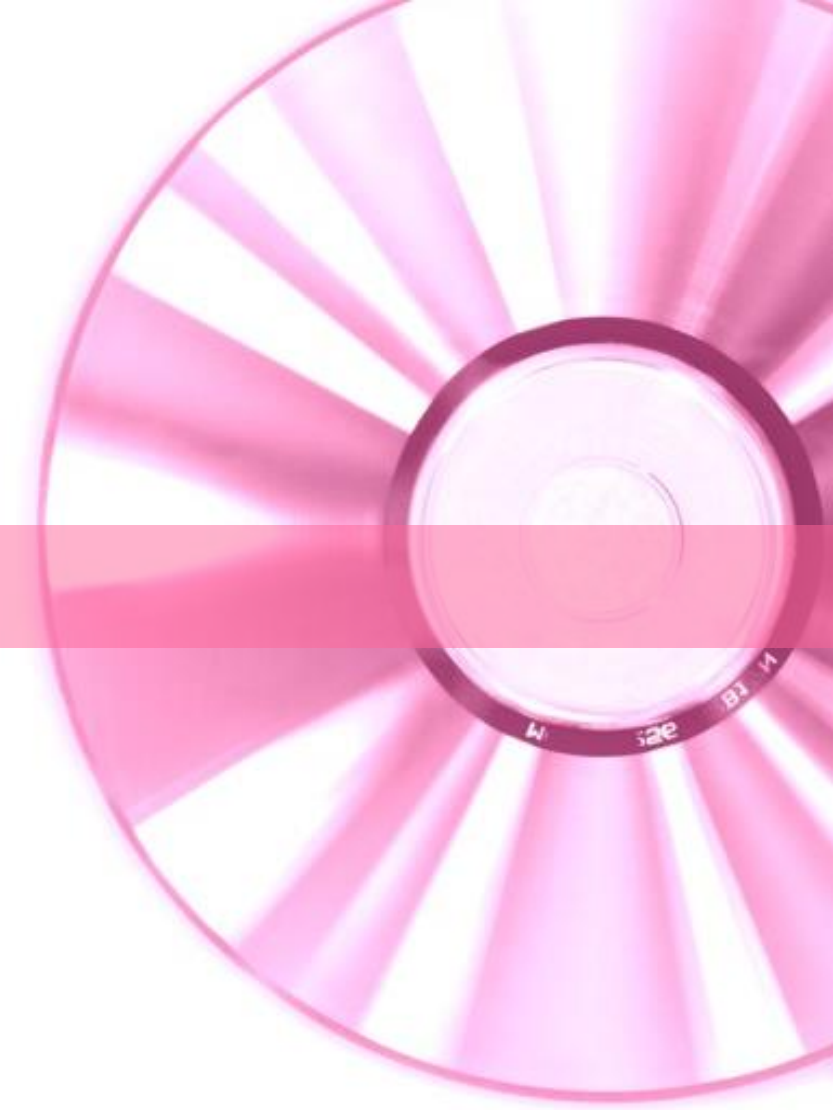
Photonics

Gaussian beam optics

Diffraction of a coherent beam

Gaussian beams and lens systems

Coherence and M^2 factor



Monochromatic light beam (in 2D)

- Helmholtz equation:

$$\nabla^2 U + k^2 U = 0$$

Solution: inhomogeneous plane wave

$$U(x, z) = A(x, z)e^{-jkz}$$

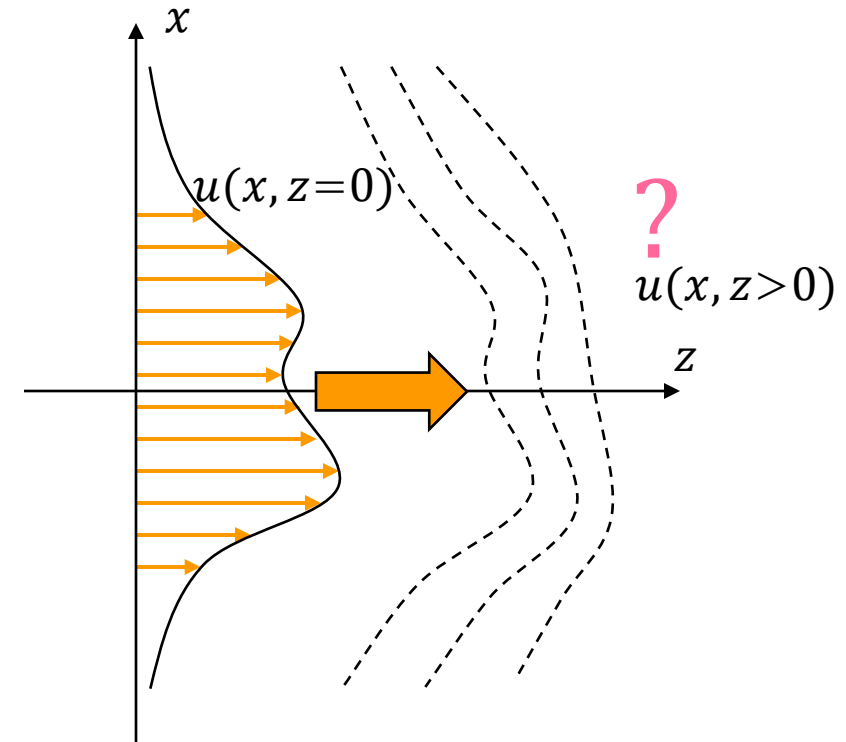
- Paraxial approximation:

$$\left| \frac{\partial^2 A}{\partial z^2} \right| \ll k \left| \frac{\partial A}{\partial z} \right|$$

Paraxial Helmholtz equation:

$$\frac{\partial^2 A}{\partial x^2} - 2jk \frac{\partial A}{\partial z} = 0$$

Change of the amplitude profile during propagation = diffraction



Gaussian beam

- Paraxial Helmholtz equation:

$$\frac{\partial^2 A}{\partial x^2} - 2jk \frac{\partial A}{\partial z} = 0$$

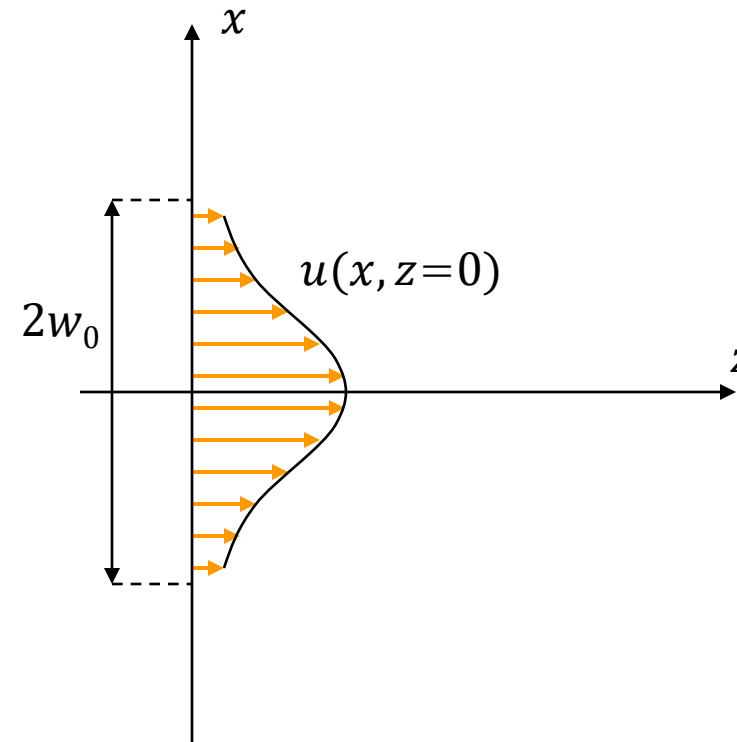
- Possible solution:
Gaussian amplitude profile at $z = 0$

$$A(x, z = 0) = e^{-\frac{x^2}{w_0^2}}$$

- beam width $2w_0$
- Perfect coherent beam
- Assumption for a solution at $z > 0$

$$A(x, z) = e^{-j\left[p(z) + k\frac{x^2}{2q(z)}\right]}$$

- beam remains Gaussian during propagation
- $p(z)$: complex phase shift along the z -axis
- $q(z)$: phase curvature and transversal amplitude profile



Diffraction of a Gaussian beam (1)

- Substitution of a Gaussian beam in the Helmholtz equation:

$$2k \left(\frac{dp}{dz} + \frac{j}{2q} \right) + \left(\frac{kx}{q} \right)^2 \left(1 - \frac{dq}{dz} \right) = 0$$

- Should hold for all x and all z :

$$\begin{cases} \frac{dq}{dz} = 1 \\ \frac{dp}{dz} = -\frac{j}{2q} \end{cases}$$

with boundary conditions ($z = 0$):

$$\begin{cases} q(0) = j \frac{kw_0^2}{2} \\ p(0) = 0 \end{cases}$$

- Integration gives:

$$q(z) = z + j \frac{kw_0^2}{2}$$

$$jp(z) = -\ln \left(\sqrt{\frac{w_0}{w(z)}} \right) - \frac{j}{2} \arctan \left(\frac{z}{b_0} \right)$$

$$A(x, z=0) = e^{-\frac{x^2}{w_0^2}}$$

$$A(x, z) = e^{-j \left[p(z) + k \frac{x^2}{2q(z)} \right]}$$

Diffraction of a Gaussian beam (2)

- Solution for $q(z)$ gives:

$$q(z) = z + j \frac{k w_0^2}{2}$$

- We can split $\frac{1}{q(z)}$ into a real and imaginary part:

$$\frac{1}{q(z)} \triangleq \frac{1}{R(z)} - j \frac{2}{k w^2(z)}$$

- $R(z)$: radius of curvature of the phase front (paraxial approximation)
- $w(z)$: half $1/e^2$ width of a Gaussian beam at z

$$R(z) = z \left(1 + \frac{b_0^2}{z^2} \right)$$

$$w(z) = w_0 \sqrt{1 + \frac{z^2}{b_0^2}}$$

where $b_0 = \frac{k w_0^2}{2} = \frac{\pi w_0^2}{\lambda}$: the Rayleigh range

Diffraction of a Gaussian beam (3)

- Solution of the wave equation:

$$U(x, z) = A(x, z)e^{-jkz}$$

$$A(x, z) = \sqrt{\frac{w_0}{w(z)}} e^{-\frac{x^2}{w^2(z)}} e^{-j\frac{kx^2}{2R(z)}} e^{j\frac{1}{2}\arctan\frac{z}{b_0}}$$

- Radius of curvature $R(z)$:

- For $z = 0$: $R(0) = \infty$

- Minimum: $R(b_0) = 2b_0$

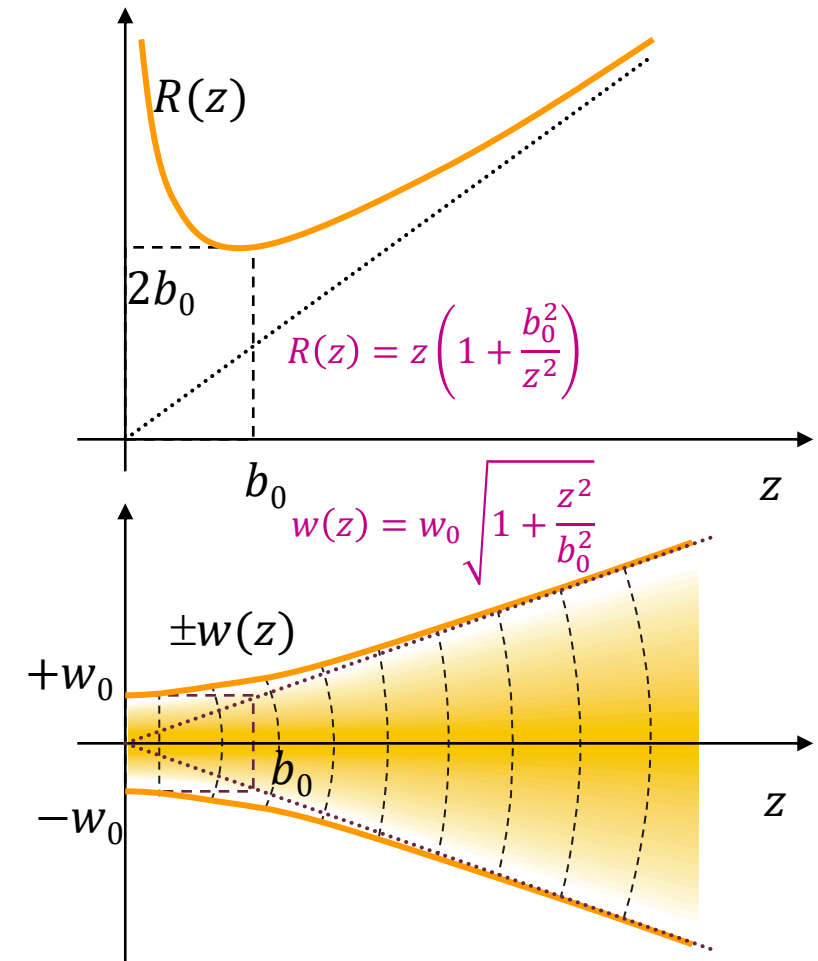
- For $z \rightarrow \infty$: $R(z) = z$

- Width $w(z)$:

- Always increases: $w(z) > w_0$

- For $z < b_0$: $w(z) \simeq w_0$

- For $z > b_0$: $w(z) \simeq z \frac{w_0}{b_0}$



The Rayleigh range

- b_0 is the *Rayleigh range*

- $z < b_0$

- Quasi constant width

$$w(b_0) = \sqrt{2}w_0$$

- Wave front begins to bend

- $z > b_0$

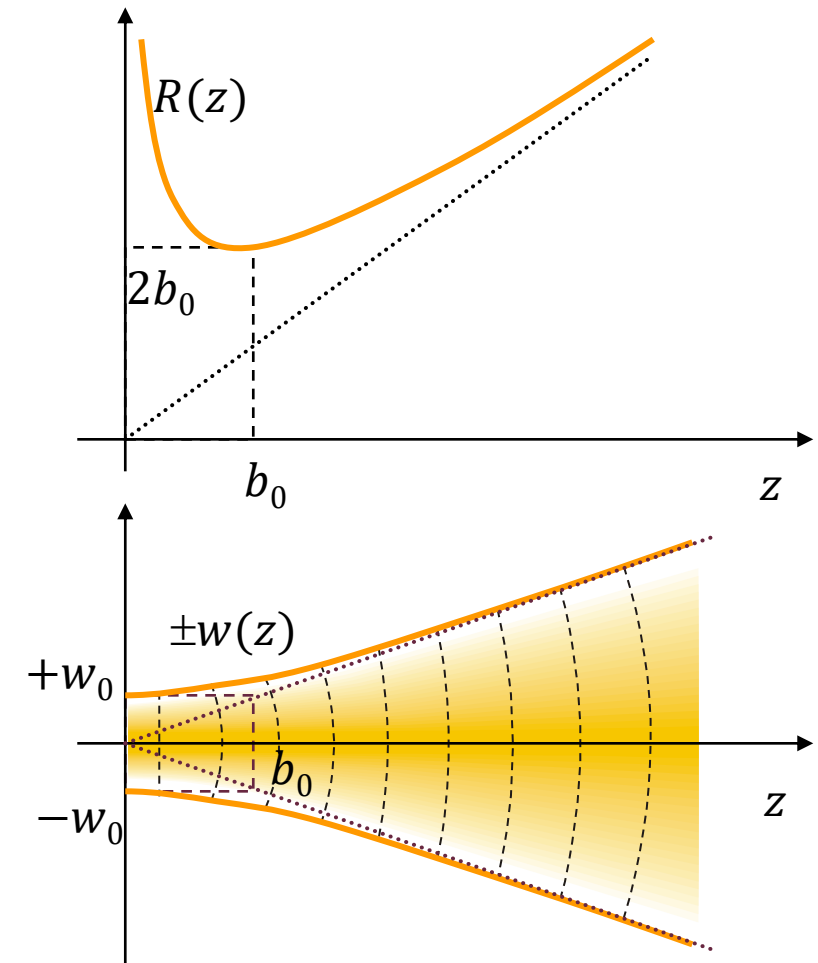
- Spherical fan out

θ = half divergence angle

$$\theta = \pm \arctan \frac{w_0}{b_0}$$

$$\simeq \pm \frac{w_0}{b_0} = \pm \frac{2}{kw_0} = \pm \frac{\lambda}{\pi w_0}$$

- Evolution to spherical wave front with center in $z = 0$



Transition from 2D to 3D

- Solution of the wave equation in 2D:

$$U(x, z) = A(x, z)e^{-jkz}$$

$$A(x, z) = \sqrt{\frac{w_0}{w(z)}} e^{-\frac{x^2}{w^2(z)}} e^{-j\frac{kx^2}{2R(z)}} e^{\frac{j}{2} \arctan \frac{z}{b_0}}$$

- Solution in 3D (for a circular beam)

$$U(x, y, z) = A(x, y, z)e^{-jkz}$$

$$A(x, y, z) = \sqrt{\frac{w_0}{w(z)}} e^{-\frac{x^2}{w^2(z)}} e^{-j\frac{kx^2}{2R(z)}} \sqrt{\frac{w_0}{w(z)}} e^{-\frac{y^2}{w^2(z)}} e^{-j\frac{ky^2}{2R(z)}} e^{\frac{j}{2} \arctan \frac{z}{b_0}}$$

$$= \frac{w_0}{w(z)} e^{-\frac{x^2+y^2}{w^2(z)}} e^{-jk\frac{x^2+y^2}{2R(z)}} e^{\frac{j}{2} \arctan \frac{z}{b_0}}$$

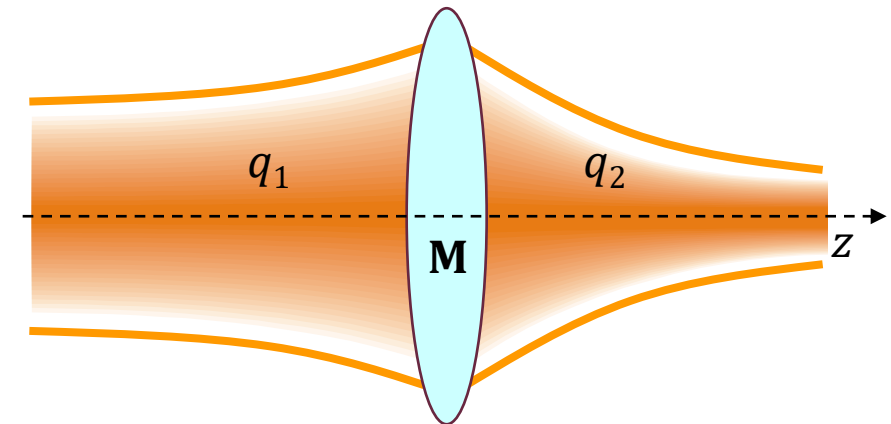
Gaussian beams and lens systems

- Gaussian beam through a thin lens:
 - again Gaussian beam
 - different phase curvature
- Gaussian beam after an arbitrary lens system
 - Incident beam: q_1
 - Lens system matrix \mathbf{M}

$$\mathbf{M} = \begin{bmatrix} A & B \\ C & D \end{bmatrix}$$

- Outgoing beam q_2

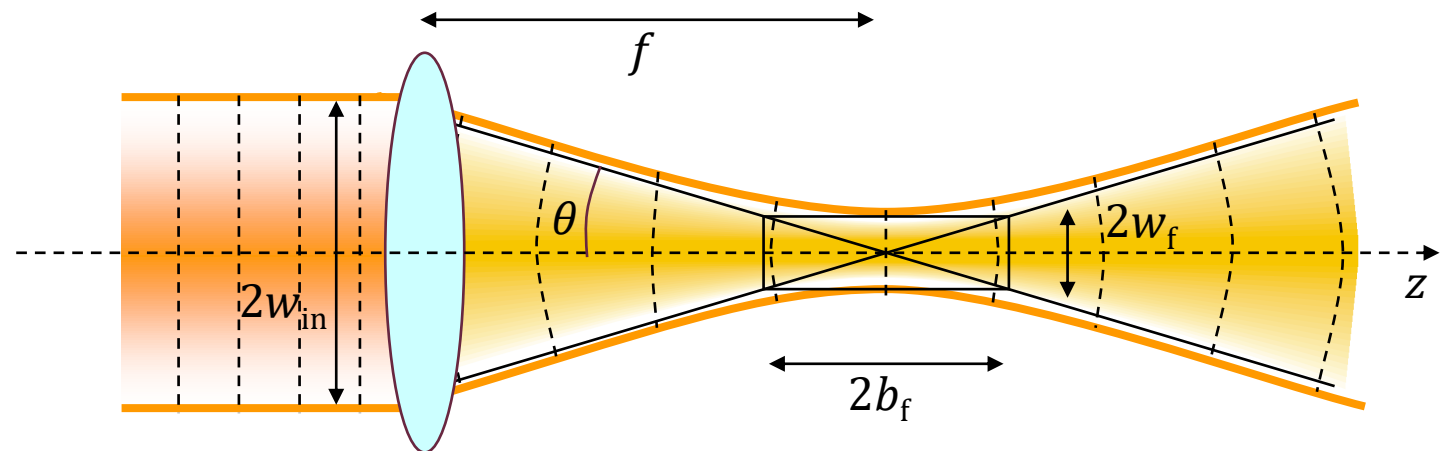
$$q_2 = \frac{Aq_1 + B}{Cq_1 + D}$$



Focusing a Gaussian beam (1)

- Incident laser beam:
 - plane phase front
 - width w_{in}
- Outgoing beam
 - converges with an angle $\theta = \frac{w_{\text{in}}}{f}$
 - θ is correlated with the w_f in the focus plane $\theta = \frac{\lambda}{\pi w_f}$

$$\theta = \frac{\lambda}{\pi w_0}$$



Focusing a Gaussian beam (2)

- The width in the focus plane: $2w_f = \frac{2\lambda f}{\pi w_{in}}$
- small spot: small focal length \rightarrow strong refraction
- If the beam is as wide as the lens:

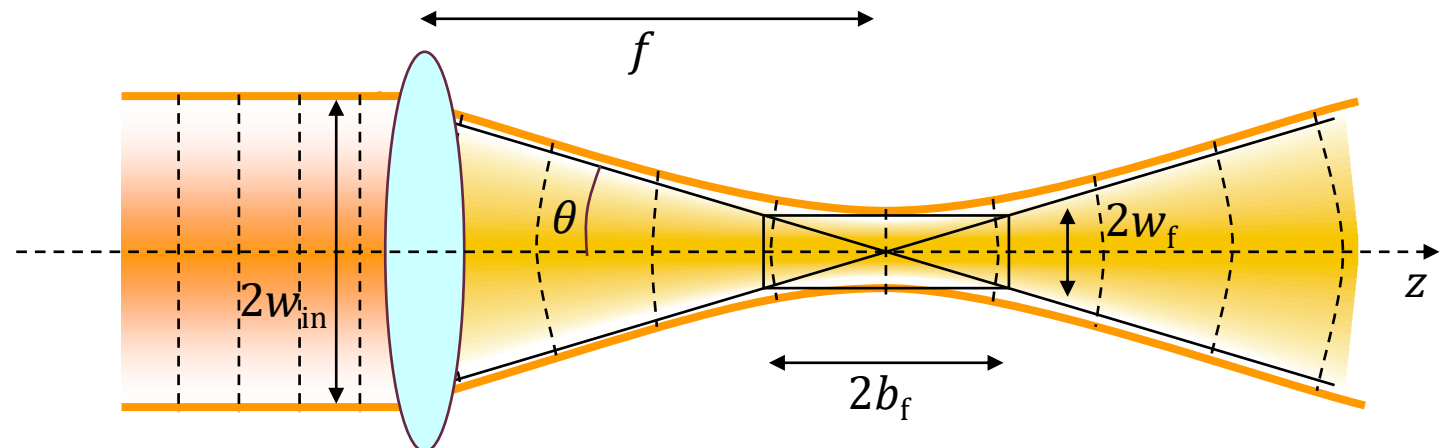
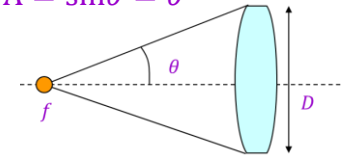
$$\theta = NA_{lens}$$

$$2w_f = \frac{2\lambda}{\pi NA_{lens}} = \frac{0.64\lambda}{NA}$$

- Depth of field $2b_f$ (the Rayleigh range): $2b_f = kw_f^2$

- Numerical aperture

$$NA = \sin\theta \approx \theta$$



$$\theta = \frac{w_{in}}{f}$$

$$b_0 = \frac{\pi w_0^2}{\lambda}$$

Focusing a Gaussian beam (3)

$$2w_f = \frac{0.64\lambda}{\text{NA}} \simeq \lambda$$

- It is impossible to focus a beam by a focusing lens system into a spot that is (substantially) smaller than the wavelength.
- To obtain smallest possible spot a lens with largest possible NA should be used
- It holds not only for Gaussian beams, but is valid in general

Focusing a Gaussian beam (3)

- Application: Bit density on a CD
- 1 CD: capacity = $750 \text{ MB} \times 17/8 \times 36/24$ (error correction)
 $= 1.9 \cdot 10^{10} \text{ bits}$
- 1 CD: area = $\pi \times (5.8^2 - 2.5^2) \text{ cm}^2$
 $= 86 \text{ cm}^2 = 86 \cdot 10^8 \mu\text{m}^2$

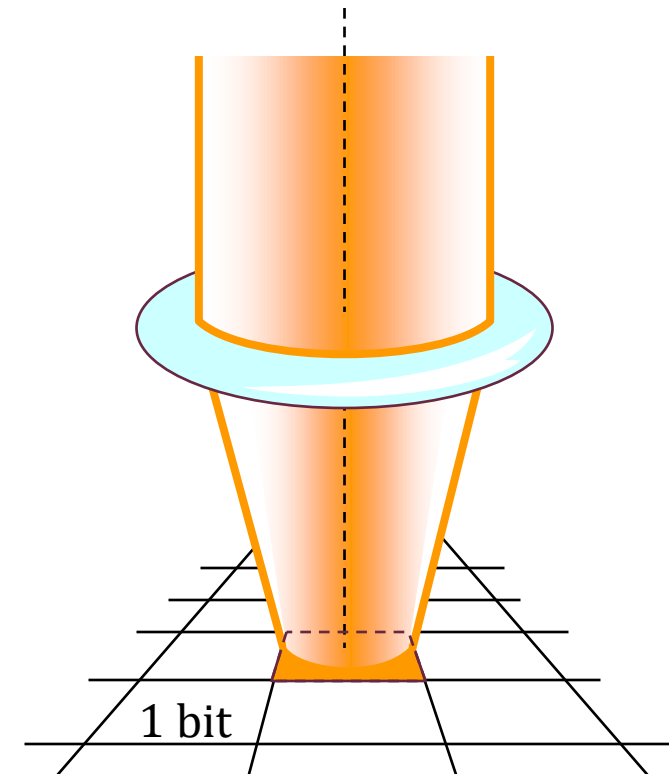
Bit density:

$$\frac{1.9 \cdot 10^{10} \text{ bits}}{86 \cdot 10^8 \mu\text{m}^2} = 2.2 \frac{\text{bits}}{\mu\text{m}^2}$$

- Physical limit:
 - wavelength $\lambda = 0.78 \mu\text{m}$
 - 1 bit \simeq circle with diameter λ
 - Bit density: $\approx 2.1 \text{ bit} / \mu\text{m}^2$
 - The only way to increase the density: decrease the wavelength

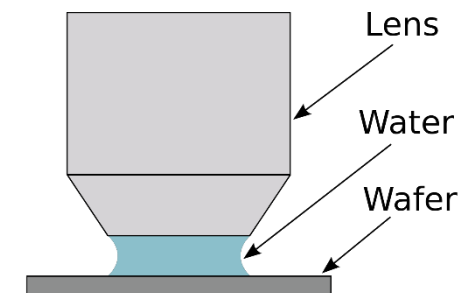


15 mm inner diameter
12 cm outer diameter
Beethoven's 9th

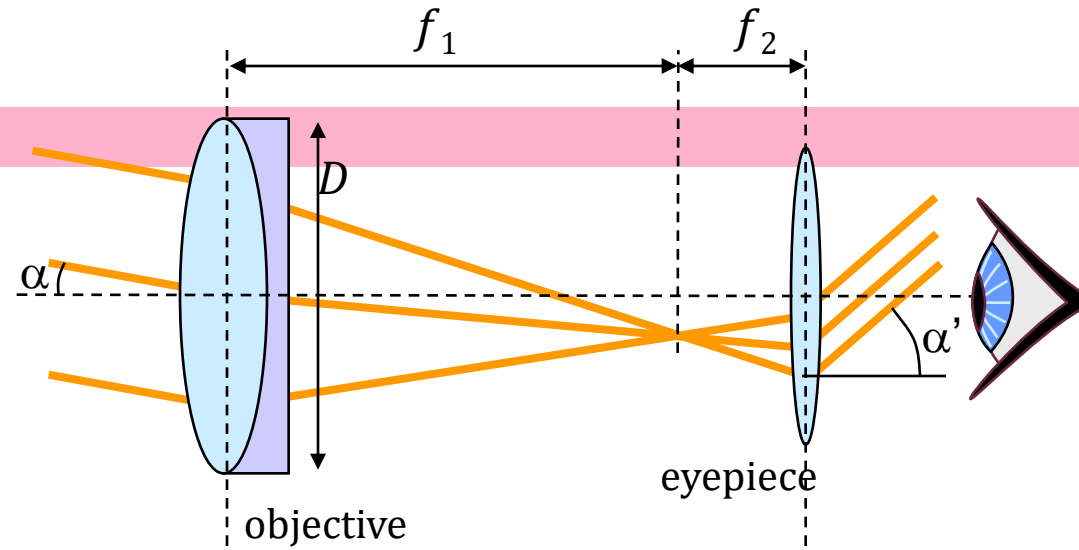


Pattern definition at IC production

- Imaging of a mask on a wafer with $4 \times$ reduction
- Source: 193 nm excimer laser (deep UV)
- NA close to 1
- Smallest feature: $0.64 \lambda = 120 \text{ nm}$
- In practice 90 nm achieved!!!
- Improvements:
 - Immersion lithography: water between the lens and a wafer: smallest feature: $0.64 \lambda/n$
 - Source with a shorter wavelength: EUV (13.5 nm)



Telescopes



- Resolution at the image plane after objective: $2w_f \approx 0.64\lambda/\text{NA}$
- It corresponds to the angular resolution in the object plane
- Diameter of the objective lens is the determining factor for the resolution (and for the light intensity as well)

$$\Delta\alpha \approx 0.64 \frac{\lambda/\text{NA}}{f_1} \approx 1.28 \frac{\lambda}{D}$$

M² factor

- Gaussian beams: $\theta = \frac{\lambda}{\pi w_0}$
- Therefore: $\pi\theta \frac{w_0}{\lambda} = 1$
- Non-Gaussian beams
 - Amplitude profile is not Gaussian
 - And/or phase profile is not parabolic: $\pi\theta \frac{w_0}{\lambda} \geq 1$
- Definition: $M^2 = \pi\theta \frac{w_0}{\lambda} \geq 1$
 - M^2 is a measure for a beam quality
 - $M^2 = 1$: “diffraction-limited beam” (it means: θ is minimal for a given beam width)

